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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.		
10/658,291	09/10/2003	Naoyuki Tamura	648.41957CX1	2459		
20457	7590 10/19/2005		EXAMINER			
	I, TERRY, STOUT & SEVENTEENTH STRE	MOORE, KARLA A				
SUITE 1800	SEVENTEENTH STRE	ART UNIT	PAPER NUMBER			
ARLINGTON	I, VA 22209-3873	1763				
			DATE MAILED: 10/19/2005			

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application N	o.	Applicant(s)	
Office Action Summary		10/658,291	0/658,291 TAMURA, NAOYU		KI
		Examiner		Art Unit	
	·	Karla Moore		1763	
The MA	AILING DATE of this communicati	on appears on the cov	er sheet with the co	rrespondence add	iress
WHICHEVER - Extensions of tim after SIX (6) MON - If NO period for re - Failure to reply w Any reply receive	ED STATUTORY PERIOD FOR IS LONGER, FROM THE MAILI e may be available under the provisions of 37 ITHS from the mailing date of this communica pely is specified above, the maximum statutorithin the set or extended period for reply will, but by the Office later than three months after the madjustment. See 37 CFR 1.704(b).	NG DATE OF THIS C CFR 1.136(a). In no event, ho tion. y period will apply and will expir y statute, cause the application	COMMUNICATION wever, may a reply be time re SIX (6) MONTHS from the to become ABANDONED	Bly filed the mailing date of this col (35 U.S.C. § 133).	
Status					
2a)☐ This act 3)☐ Since th	sive to communication(s) filed or ion is <b>FINAL</b> . 2b) is application is in condition for an accordance with the practice u	This action is non-fi	ormal matters, pros		merits is
Disposition of CI	aims				
4a) Of th 5) ☐ Claim(s) 6) ☑ Claim(s) 7) ☐ Claim(s)	5-8 is/are pending in the applicate above claim(s) is/are w is/are allowed.  5-8 is/are rejected.  is/are objected to.  are subject to restriction	ithdrawn from conside			
10)⊠ The draw Applicant Replacen	cification is objected to by the Exving(s) filed on 10 September 20 may not request that any objection nent drawing sheet(s) including the or declaration is objected to by	<u>03</u> is/are: a)⊠ accept to the drawing(s) be hel correction is required if t	d in abeyance. See he drawing(s) is obje	37 CFR 1.85(a). ected to. See 37 CFI	R 1.121(d).
Priority under 35	U.S.C. § 119				
a)⊠ All b 1.□ Ce 2.⊠ Ce 3.□ Ce ap	edgment is made of a claim for for local some * c) None of:  Pertified copies of the priority document of the priority document of the priority document of the certified copies of the priority document of the certified copies of the polication from the International Extrached detailed Office action for	uments have been red uments have been red e priority documents I Bureau (PCT Rule 17.	ceived. ceived in Application nave been received 2(a)).	n No. <u>10/218,406</u> I in this National S	
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Attachment(s)					
Notice of Refere     Notice of Draftsp     Information Disc	nces Cited (PTO-892) person's Patent Drawing Review (PTO-9 losure Statement(s) (PTO-1449 or PTO/	4) [ 48) SB/08) 5) [	Interview Summary (F Paper No(s)/Mail Date Notice of Informal Pat	ө	-152)
Paper No(s)/Mail	Date		Other:		•

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#### **DETAILED ACTION**

### Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 5-8 are rejected under 35 U.S.C. 102(b) as being anticipated by U.S. Patent No. 6,198,976 to Sundar et al.
- 3. Sundar et al. disclose a vacuum processing method for transferring a wafer in atmospheric air to a predetermined position within a vacuum processing chamber (Figure 2B, 114) using a atmospheric equipment (128) disposed in an atmospheric transfer unit (120) and performing a predetermined treatment to said wafer in said vacuum processing chamber; said method comprising: an atmospheric transfer step (column 12, rows 50-54 and rows 58-60) of transferring said wafer in atmospheric air to a said vacuum transfer chamber (112) using an atmospheric transfer equipment disposed in atmospheric air; a vacuum transfer step (column 12, rows 60-63) of transferring a wafer received from said atmospheric transfer equipment to a position for said predetermined treatment within said vacuum processing chamber using vacuum transfer equipment (116) disposed within said vacuum transfer chamber connecting said atmospheric transfer unit and said vacuum processing chamber; a step of detecting the displacement of said wafer (column 12, rows 63-65) in a transverse direction (the displacement can be detected while moving any direction) with respect to a traveling direction near an ingress path of said wafer to said vacuum processing chamber by comparing a correct position said wafer passing a line which is predetermined in advance with an actual position of said wafer being transferred by said vacuum transfer equipment; and a step of moving a vacuum robot of said vacuum transfer equipment (column 6, rows 27-38) which transfers said wafer in the transverse direction with respect to the traveling direction as to correct the detected displacement of the wafer (or a step of correcting the displacement of said wafer by moving an arm of said vacuum transfer equipment in the transverse

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direction with respect to the traveling direction based on the result of detection performed by a wafer position sensor, which is commensurate with the prior step).

4. With respect to claim 7/5 and 7/6, said step of detecting the displacement of said wafer comprises a step of detecting the rim position of said wafer being transferred in the vacuum transfer step (column 5, rows 1-3).

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5. With respect to claim 8/5 and 8/6, initial positioning of said wafer is performed in atmosphere (), and the displacement of said wafer is detected directly before the processing within said vacuum processing chamber (column 11, rows 1-18).

#### Response to Arguments

6. Applicant's arguments with respect to claims 5-8 have been considered but are most in view of the new ground(s) of rejection. New art has been relied upon to account for the amended claims.

## Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Karla Moore whose telephone number is 571.272.1440. The examiner can normally be reached on Monday-Friday, 8:30am-5:30pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on 571.272.1435. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Karla Moore Patent Examiner 17 October 2005